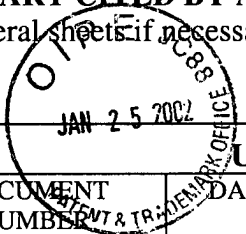
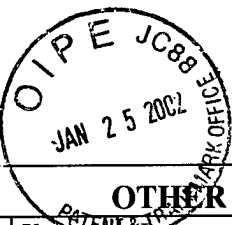


FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE										AGENT DOCKET NO. ONX-106A		SERIAL NO. 09/810,336		
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)										APPLICANT Behrang Behin et al.				
										FILING DATE 3/14/2001		GROUP 2811		
<div style="text-align: center;">  U.S. PATENT DOCUMENTS </div>														
EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
<i>but</i>	A	5	7	2	3	3	5	3	3/3/1998	Muenzel et al.	437	51	2/12/1996	
<i>but</i>	B	5	7	2	6	0	7	3	3/10/1998	Zhang et al.	437	228	1/16/1996	
<i>but</i>	C	5	7	5	3	9	1	1	5/19/1998	Yasuda et al.	250	306	1/16/1997	
<i>but</i>	D	5	8	7	2	8	8	0	2/16/1999	Maynard	385	88	8/12/1996	
<i>but</i>	E	6	3	3	0	1	0	2	12/11/2001	Daneman et al.	359	290	3/25/2000	
<i>but</i>	F	5	9	5	9	7	6	0	9/28/1999	Yamada et al.	359	224	7/28/1998	
FOREIGN PATENT DOCUMENTS														
		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
													YES NO	
<i>but</i>	G	0	9	0	7	0	7	6	A 2	4/7/1999	Europe	G01N	27/00	
<i>but</i>	H	0	9	0	7	0	7	6	A 3	10/4/2000	Europe	H01J	37/63	
<i>but</i>	I	0	9	1	1	9	5	2	A 2	4/28/1999	Europe	H02N	1/00	
<i>but</i>	J	0	9	1	1	9	5	2	A 3	4/5/2000	Europe	H02N	1/00	
<i>but</i>	K	1	9	7	5	7	1	8	1 A	7/1/1997	Germany	G02B	6/35	X
<i>but</i>	L	1	9	6	4	4	9	1	8 A	4/30/1998	Germany	G02B	6/35	X
<i>but</i>	M	2	9	6	1	1	8	8	1 8	12/12/1996	Germany	G02B	6/35	X
<i>but</i>	O	2	7	3	2	4	6	7	A 1	4/10/1996	France	G01P	15/08	X
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)														
<i>but</i>	N	"Electrostatic Comb Drive For Vertical Actuation" A.P. Lee et al., Proceedings of the SPIE, SPIE, Bellingham, VA, vol. 3224, Sept 29, 1997, pp 109-119												
<i>but</i>	P	"Design, Fabrication, Position Sensing, And Control Of An Electrostatically-Driven Polysilicon Microactuator," P. Cheung et al, IEEE Transactions on Magnetics, vol. 32, no. 1, 1 Jan. 1996, pp 122-128												
<i>but</i>	Q	"Optical Methods For Micromachine Monitoring And Feedback", F.M. Dickey et al., Sensors and Actuators, vol. 78, 1999, pp 220-235												
<i>but</i>	R	"A High Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension", Selvakumar et al., Journal of Microelectromechanical Systems, IEEE Inc., New York, vol. 7, No. 2, June 1998, pp 192-200												
<i>but</i>	S	"MEMS Fabrication of High Aspect Ratio Track-Following Micro Actuator for Hard Disk Drive Using Silicon On Insulator", B. H. Kim et al., Technical Digest of the IEEE International MEMS '99 Conference. 12 th IEEE International Conference on Micro Electro Mechanical Systems. Orlando, FL, Jan 17-21, 1999, IEEE International Micro Electro Mechanical Systems Conference, New York, NY, 1999, pp 53-56.												
<i>but</i>	T	"Fabrication of Comb-Shaped Microactuator for Multi-Degrees-of-Freedom System", F. Fujikawa et al., Robotics, CIM and Automation, Emerging Technologies, San Diego, Nov. 9-13, 1992, Proceedings of the International Conference on Industrial Electronics, Control, Instrumentation and Automation (IECON), New York, NY, IEEE, US, vol. 2 Conf 18, 9 November 1992, pp 990-995												
EXAMINER										DATE CONSIDERED				
<i>[Signature]</i>										9/19/02				
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.														

**OTHER PRIOR ART** (Including Author, Title, Date, Pertinent Pages, Etc.)

7	but	U	"Integrated Micro-Scanning Tunneling Microscope", Xu et al., Applied Physics Letters, American Institute of Physics, New York, vol. 67, No. 16, October 16, 1995 pp 2305-2307.
8	but	V	B. Behin et al., US Published Patent Application US-2001-002001-0048784-A1, Published Dec. 6, 2001, Serial No. 09/751,660 "Two-Dimensional Gimbaled Scanning Actuator with Vertical Electrostatic Comb-Drive for Actuation and/or Sensing" Filed Dec 28, 2000 (ONX-105)
9	but	W	B. Behin et al., US Patent Application Serial No. 09/809,994 "Biased Rotatable Combdribe Actuator Methods" Filed March 14, 2001 (ONX-106B)
10	but	X	B. Behin et al., US Published Patent Application US-2001-002001-0040419-A1, Published Nov. 15, 2001, Serial No. 09/809,995 "Biased Rotatable Combdribe Sensor Methods", Filed March 14, 2001 (ONX-106C)
11	but	Y	B. Behin et al., US Published Patent Application, US-2001-002001-0051014-A1, Published Dec. 13, 2001, Serial No. 09/810,326 "Optical Switch Employing Biased Rotatable Combdribe Devices and Methods", Filed March 14, 2001 (ONX-106D)
12	but	Z	B. Behin et al., US Patent Application Serial No. 09/810,333 "Multi-Layer, Self-Aligned Vertical Combdribe Electrostatic Actuators And Fabrication Methods", Filed March 14, 2001 (ONX-107A)
13	but	AA	B. Behin et al., US Published Patent Application US-2001-002001-0034938-A1, Serial No. 09/810,335 "Multi-Layer, Self-Aligned Vertical Combdribe Electrostatic Actuators And Fabrication Methods", Filed March 14, 2001 (ONX-107B)
14	but	AB	"Vertical Comb Array MicroActuators", A. Selvakumar et al., Proceedings of the Workshop on Micro Electrical Mechanical Systems (MEMS), Amsterdam, New York, Jan 29-Feb 2, 1995, IEEE Vol. Workshop 8 Jan. 29, 1995, pp 43-48, ISBN 0-7803-2504-4
15	but	AC	"Fabrication of a 3D Differential-Capacitive Acceleration Sensor by UV-LIGA", W. Qu et al., Sensors and Actuators 77 (1999), pp 14-20, Elsevier Science, 0924-4247/99/\$
16	but	AD	"Integrating SCREAM Micromachined Devices with Integrated Circuits", K.A. Shaw, N.C MacDonald, IEEE MEMS '96, San Diego, California 1996, IEEE Publication 0-7803-2985-6/96, pp 44-48
17	but	AE	"An electrostatically excited 2D-Micro-Scanning-Mirror with an in-plane configuration of the driving electrodes", H. Schenk et al., MEMS 2000, 13 th Int. Micro Electro Mechanical Systems Conf, Miyazaki, Japan, p. 473-478 (2000).
18	but	AF	"Damping of Micro Electrostatic Torsion Mirror Caused by Air-Film Viscosity", N. Uchida et al.
19	but	AG	"Single Crystal Silicon (SCS) MicroMirror Arrays using Deep Silicon Etching and IR Alignment", C.S.B. Lee et al.

EXAMINER**DATE CONSIDERED**

9/19/02

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